

Form PTO-1449	ATTY. DOCKET NO. 0104-0279P	APPLICATION NO. 09/623,195
INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)		
APPLICANT Torbjorn SANDSTROM		
FILING DATE August 29, 2000		GROUP 2873

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	Kind	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
W.C.	US 4 566 935		1986-01-28	Hornbeck	438	29	
	US 5 296 891		1994-03-22	Vogt et al.	355	67	
	US 5 504 504		1996-04-02	Markandey et al.	245	214	
	US 5 508 B41		1996-04-16	Lin et al.	259	318	
	US 5 539 567		1996-07-23	Lin et al.	359	281	
	US 5 539 568		1996-07-23	Lin et al.	359	285	
	US 5 835 256		1998-11-10	Huibers	359	291	
	US 6 060 224		2000-05-09	Sweatt et al.	420	295	
	US 6 285 488		2001-09-04	Sanstrom	359	290	
	US 6 373 619		2002-04-16	Sandstrom	359	298	
	6 428 940		2002-08-06	Sandstrom	420	22	
	6 489 984		2002-12-03	Johnson	247	239	

FOREIGN PATENT DOCUMENTS

	Office	DOCUMENT NUMBER	Kind	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION	
								YES	NO
W.C.	WO 93	09469		1993-05-13	WIPO			X	
	EP	0 467 076		1992-01-22	EP			X	
	WO 99	45439		1999-09-10	WIPO			X	
	WO 00	42618		2000-07-20	WIPO			X	
	WO 98	04950		1998-02-05	WIPO			X	
	WO 99	22262		1999-05-06	WIPO			X	
	WO 99	45441		1999-09-10	WIPO			X	

OTHER DOCUMENTS (Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.)

L.C.	H. KUCK et al., New System for fast submicron laser direct writing, SPIE Vol. 2440, pgs 506-514
W.C.	P.M. HAGELEN et al., Micromachining and microfabrication technology for adaptive optics, os 9/16/99
EXAMINER <i>20</i> DATE CONSIDERED <i>1/8/04</i>	
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 409. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	